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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

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Sheet 2 of 2

**Complete if Known**

Application Number	10/562666
Filing Date	
First Named Inventor	Lionel Oisel et al.
Art Unit	
Examiner Name	
Attorney Docket Number	PF030104

**NON PATENT LITERATURE DOCUMENTS**

Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	AC	R.T. Collins et al: "Matching perspective views of coplanar structures using projective unwarping and similarity matching", COMPUTER VISION AND PATTERN RECOGNITION, 1993, PROCEEDINGS CVPR '93, LOA ALAMITOS, CA. USA, 15 June 1993, pages 240-245	
	AD	D. Chetverikov et al.: "Matching for shape defect detection", LECTURE NOTES IN COMPUTER SCIENCES, vol. 1689, 1999, pages 367-374	
	AE	Z. Zhang: "DETERMINING THE EPIPOLAR GEOMETRY AND ITS UNCERTAINTY: A REVIEW", INTERNATIONAL JOURNAL OF COMPUTER VISION, KLUWER ACADEMIC PUBLISHERS, NORWALL, US, vol. 27, no. 2, 1 March 1998, pages 161-195	
	AF	D-G. Sim et al: "OBJECT MATCHING ALGORITHMS USING ROBUST HAUSDORFF DISTANCE MEASURES", IEEE TRANSACTIONS ON IMAGE PROCESSING, IEEE INC., NEW YORK, US, vol. 8, no. 3, March 1999, pages 425-429	
	AG	D.-K. Kim, et al.: "A planar perspective image matching using point correspondences and rectangle to quadrilateral mapping" FIFTH IEEE SOUTHWEST SYMPOSIUM ON IMAGE ANALYSIS AND INTERPRETATION, 2002, pages 87-91	
	AH	O. Faugeras: "Three dimensional computer vision-a geometric viewpoint", 1993, MIT PRESS, pages 98-102	
		COPY OF SEARCH REPORT DATED NOVEMBE5, 5, 2004	

Examiner Signature		Date Considered	
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> Applicant is to place a check mark here if English language Translation is attached.

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